



INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Attorney Docket Number	7276-78462-01
Application Number	10/777,282
Filing Date	February 10, 2004
First Named Inventor	Adams
Art Unit	1797
Examiner Name	Keri A. Moss

U.S. PATENT DOCUMENTS

Copies of U.S. Patent documents do not need to be provided, unless requested by the Patent and Trademark Office. For patents, provide the patent number and the issue date. For published U.S. applications, provide the publication number and the publication date. For unpublished pending patent applications, provide the application number and the filing date.

Examiner's Initials*	Cite No. (optional)	Number	Publication Date	Name of Applicant or Patentee
/K.M./		3,164,004	January 5, 1965	KING
/K.M./		3,266,291	August 16, 1966	KING
/K.M./		3,478,573	November 18, 1969	KING
/K.M./		3,715,911	February 13, 1973	CHUAN
/K.M./		4,312,288	January 26, 1982	FINSTERWALDER ET AL.
/K.M./		4,549,427	October 29, 1985	KOLESAR, JR.
/K.M./		4,637,987	January 20, 1987	MINTEN ET AL.
/K.M./		4,674,319	June 23, 1987	MULLER ET AL.
/K.M./		4,935,634	June 19, 1990	HANSMA ET AL.
/K.M./		4,992,244	February 12, 1991	GRATE
/K.M./		5,266,801	November 30, 1993	ELINGS ET AL.
/K.M./		5,345,213	September 6, 1994	SEMANCIK ET AL.
/K.M./		5,356,756	October 18, 1994	CAVICCHI ET AL.
/K.M./		5,411,709	May 2, 1995	FURUKI ET AL.
/K.M./		5,412,980	May 9, 1995	ELINGS ET AL.
/K.M./		5,445,008	August 29, 1995	WACHTER ET AL.
/K.M./		5,469,369	November 21, 1995	ROSE-PEHRSSON ET AL.

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/K.M./		5,519,212	May 21, 1996	ELINGS <i>ET AL.</i>
/K.M./		5,719,324	February 17, 1998	THUNDAT <i>ET AL.</i>
/K.M./		5,742,377	April 21, 1998	MINNE <i>ET AL.</i>
/K.M./		5,750,989	May 12, 1998	LINDSAY <i>ET AL.</i>
/K.M./		5,753,814	May 19, 1998	HAN <i>ET AL.</i>
/K.M./		5,756,631	May 26, 1998	GRATE
/K.M./		5,807,758	September 15, 1998	LEE <i>ET AL.</i>
/K.M./		5,874,668	February 23, 1999	XU <i>ET AL.</i>
/K.M./		5,883,705	March 16, 1999	MINNE <i>ET AL.</i>
/K.M./		5,918,263	June 29, 1999	THUNDAT
/K.M./		5,965,452	October 12, 1999	KOVACS
/K.M./		6,005,400	December 21, 1999	THUNDAT <i>ET AL.</i>
/K.M./		6,015,869	January 18, 2000	GRATE <i>ET AL.</i>
/K.M./		6,016,686	January 25, 2000	THUNDAT
/K.M./		6,029,500	February 29, 2000	TOM
/K.M./		6,032,518	March 7, 2000	PRATER <i>ET AL.</i>
/K.M./		6,041,642	March 28, 2000	DUNCAN
/K.M./		6,050,722	April 18, 2000	THUNDAT <i>ET AL.</i>
/K.M./		6,075,585	June 13, 2000	MINNE <i>ET AL.</i>
/K.M./		6,096,559	August 1, 2000	THUNDAT <i>ET AL.</i>

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/K.M./		6,118,124	September 12, 2000	THUNDAT <i>ET AL.</i>
/K.M./		6,156,578	December 5, 2000	TOM
/K.M./		6,167,748	January 2, 2001	BRITTON JR. <i>ET AL.</i>
/K.M./		6,182,499	February 6, 2001	MCFARLAND <i>ET AL.</i>
/K.M./		6,185,992	February 13, 2001	DANIELS <i>ET AL.</i>
/K.M./		6,189,374	February 20, 2001	ADDERTON <i>ET AL.</i>
/K.M./		6,212,939	April 10, 2001	THUNDAT
/K.M./		6,253,162	June 26, 2001	JARMAN <i>ET AL.</i>
/K.M./		6,263,736	July 24, 2001	THUNDAT <i>ET AL.</i>
/K.M./		6,269,685	August 7, 2001	ODEN
/K.M./		6,280,939	August 28, 2001	ALLEN
/K.M./		6,289,717	September 18, 2001	THUNDAT <i>ET AL.</i>
/K.M./		6,295,861	October 2, 2001	TOM <i>ET AL.</i>
/K.M./		6,311,549	November 6, 2001	THUNDAT <i>ET AL.</i>
/K.M./		6,311,557	November 6, 2001	DAVIS <i>ET AL.</i>
/K.M./		6,312,959	November 6, 2001	DATSKOS
/K.M./		6,336,353	January 8, 2002	MATSIEV <i>ET AL.</i>
/K.M./		6,336,366	January 8, 2002	THUNDAT <i>ET AL.</i>
/K.M./		6,393,895	May 28, 2002	MATSIEV <i>ET AL.</i>
/K.M./		6,401,519	June 11, 2002	MCFARLAND <i>ET AL.</i>

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/K.M./		6,408,250	June 18, 2002	GRATE <i>ET AL.</i>
/K.M./		6,411,075	June 25, 2002	BATTISTON <i>ET AL.</i>
/K.M./		6,436,346	August 20, 2002	DOKTYCZ <i>ET AL.</i>
/K.M./		6,437,328	August 20, 2002	KNAUSS <i>ET AL.</i>
/K.M./		6,455,319	September 24, 2002	LEWIS <i>ET AL.</i>
/K.M./		6,457,360	October 1, 2002	DARAKTCHIEV <i>ET AL.</i>
/K.M./		6,469,293	October 22, 2002	SHIMIZU <i>ET AL.</i>
/K.M./		6,477,479	November 5, 2002	MANSKY <i>ET AL.</i>
/K.M./		6,487,523	November 26, 2002	JARMAN <i>ET AL.</i>
/K.M./		6,494,079	December 17, 2002	MATSIEV <i>ET AL.</i>
/K.M./		6,523,392	February 25, 2003	PORTER <i>ET AL.</i>
/K.M./		6,530,266	March 11, 2003	ADDERTON <i>ET AL.</i>
/K.M./		6,535,822	March 18, 2003	MANSKY <i>ET AL.</i>
/K.M./		6,535,824	March 18, 2003	MANSKY <i>ET AL.</i>
/K.M./		6,545,495	April 8, 2003	WARMACK <i>ET AL.</i>
/K.M./		6,575,020	June 10, 2003	DE CHARMOY GREY <i>ET AL.</i>
/K.M./		6,598,459	July 29, 2003	FU
/K.M./		6,606,567	August 12, 2003	GRATE <i>ET AL.</i>
/K.M./		6,650,102	November 18, 2003	HAJDUK <i>ET AL.</i>
/K.M./		6,668,627	December 30, 2003	LANGE <i>ET AL.</i>

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/K.M./		6,672,144	January 6, 2004	ADDERTON <i>ET AL.</i>
/K.M./		6,763,705	July 20, 2004	THUNDAT <i>ET AL.</i>
/K.M./		6,810,720	November 2, 2004	ADDERTON <i>ET AL.</i>
/K.M./		6,811,133	November 2, 2004	MILES
/K.M./		6,815,866	November 9, 2004	LEE
/K.M./		6,823,717	November 30, 2004	PORTER <i>ET AL.</i>
/K.M./		6,854,317	February 15, 2005	PORTER <i>ET AL.</i>
/K.M./		6,866,819	March 15, 2005	CHANDRA <i>ET AL.</i>
/K.M./		6,904,786	June 14, 2005	MATSIEV <i>ET AL.</i>
/K.M./		6,928,877	August 16, 2005	CARLSON <i>ET AL.</i>
/K.M./		6,935,165	August 30, 2005	BASHIR <i>ET AL.</i>
/K.M./		6,953,977	October 11, 2005	MLCAK <i>ET AL.</i>
/K.M./		6,955,787	October 18, 2005	HANSON
/K.M./		6,957,565	October 25, 2005	MATSIEV <i>ET AL.</i>
/K.M./		2001/0000279 A1	April 19, 2001	DANIELS <i>ET AL.</i>
/K.M./		2001/0029774 A1	October 18, 2001	GRATE <i>ET AL.</i>
/K.M./		2002/0032531 A1	March 14, 2002	MANSKY <i>ET AL.</i>
/K.M./		2002/0062684 A1	May 30, 2002	ADDERTON <i>ET AL.</i>
/K.M./		2002/0092359 A1	July 18, 2002	LANGE <i>ET AL.</i>
/K.M./		2002/0178787 A1	December 5, 2002	MATSIEV <i>ET AL.</i>

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/K.M./		2003/0000291 A1	January 2, 2003	KOLOSOV <i>ET AL.</i>
/K.M./		2003/0041653 A1	March 6, 2003	MATSIEV <i>ET AL.</i>
/K.M./		2003/0041676 A1	March 6, 2003	HAJDUK <i>ET AL.</i>
/K.M./		2003/0089182 A1	May 15, 2003	THAYSEN <i>ET AL.</i>
/K.M./		2003/0101006 A1	May 29, 2003	MANSKY <i>ET AL.</i>
/K.M./		2003/0154771 A1	August 21, 2003	DE CHARMOY GREY <i>ET AL.</i>
/K.M./		2003/0166039 A1	September 4, 2003	HUBLER <i>ET AL.</i>
/K.M./		2003/0218467 A1	November 27, 2003	CARLSON <i>ET AL.</i>
/K.M./		2004/0074303 A1	April 22, 2004	MATSIEV <i>ET AL.</i>
/K.M./		2004/0099050 A1	May 27, 2004	MATSIEV <i>ET AL.</i>
/K.M./		2004/0244487 A1	December 9, 2004	KOLOSOV <i>ET AL.</i>
/K.M./		2004/0250622 A1	December 16, 2004	KOLOSOV <i>ET AL.</i>
/K.M./		2004/0255651 A1	December 23, 2004	ADDERTON <i>ET AL.</i>
/K.M./		2005/0016276	January 27, 2005	GUAN <i>ET AL.</i>
/K.M./		2005/0034542 A1	February 17, 2005	THAYSEN
/K.M./		2005/0066714 A1	March 31, 2005	ADDERTON <i>ET AL.</i>
/K.M./		2005/0009197A1	January 13, 2005	ADAMS <i>ET AL.</i>
/K.M./		2005/0133877 A1	June 23, 2005	THAYSEN <i>ET AL.</i>
/K.M./		2005/0164299 A1	July 28, 2005	STEWART
/K.M./		2005/0166679 A1	August 4, 2005	CARLSON <i>ET AL.</i>

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/K.M./		2005/0199047A1	October 15, 2005	ADAMS <i>ET AL.</i>
/K.M./		2005/0229713 A1	October 20, 2005	NIBLOCK
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/K.M./		WIPO	WO2003/04453 0 A1	May 30, 2003	CANTION A/S <i>ET AL.</i>
/K.M./		WIPO	WO2003/06213 5 A1	July 31, 2003	CANTION A/S <i>ET AL.</i>
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/K.M./		WIPO	WO2003/07125 8 A1	August 28, 2003	CANTION A/S <i>ET AL.</i>
/K.M./		WIPO	WO2003/10478 4 A1	December 18, 2003	CANTION A/S <i>ET AL.</i>
/K.M./		WIPO	WO2004/05930 6 A1	July 15, 2004	CANTION A/S <i>ET AL.</i>
/K.M./		WIPO	WO2004/08380 2 A2	September 30, 2004	CANTION A/S <i>ET AL.</i>
/K.M./		WIPO	WO2005/08340 9 A1	September 9, 2005	CANTION A/S <i>ET AL.</i>
/K.M./		WIPO	WO2006/039506 A3	04-13-2006	BOARD OF REGENTS OF THE NEVADA SYSTEM OF HIGHER EDUCATION, ON BEHALF OF THE UNIVERSITY NEVADA RENO

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/K.M./		Abedinov, <i>et al.</i> , "Micromachined Piezoresistive Cantilever Array with Integrated Resistive Microheater for Calorimetry and Mass Detection," <i>Journal of Vacuum & Science Technology</i> 19(6); pp.2884-2888 (Nov/Dec 2001).
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/K.M./		Ali, <i>et al.</i> , "Organic Vapour Sensing Using a Coated Piezoelectric Quartz Crystal Sensor Array," <i>SPIE</i> 3853; pp.116-120 (September, 1999).
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/K.M./		Baselt <i>et al.</i> , "Biosensor Based On Force Microscope Technology," <i>J. Vac. Sci. Technol. B</i> 14(2):789-793, (Mar/Apr 1996).
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/K.M./		Berger, <i>et al.</i> , "Micromechanical Thermogravimetry," <i>Chemical Physics Letters</i> , Vol. 294:363-369 (September 18, 1998).
/K.M./		Berger, <i>et al.</i> , "Micromechanics: A Toolbox for Femtoscale Science: Towards a Laboratory on a Tip," <i>Microelectronic Engineering</i> , Vol. 35:373 (1997).
/K.M./		Berger <i>et al.</i> , "Transduction Principles and Integration of Chemical Sensors into a Micromechanical Array Device," <i>IBM Research Division Research Report</i> , (December 1997).
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/K.M./		Buck, <i>et al.</i> , "Piezoelectric Chemical Sensors," <i>Pure Appl. Chem.</i> 76(6):1139-1160 (2004).
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/K.M./		Cleland, "Single-Crystal Aluminum Nitride Nanomechanical Resonators," <i>Applied Physics Letters</i> 79(13):2070-2072 (September 24, 2001).

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/K.M./		Datskos, <i>et al.</i> , "MEMS Based Calorimetric Spectroscopy," <i>CalSpec factsheet</i> , OakRidge National Laboratory.
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